

548/2008

This is to certify that I, Marco Antônio Rochadel, Official Public Translator, designated and installed in Office according to The Official Gazette of June 23, 1982, page 5428, have received and translated, to the best of my knowledge and belief, a document with the following contents:



PRESIDENCY OF THE REPUBLIC

CIVIL AFFAIRS MINISTRY

OFFICE OF THE DEPUTY HEAD FOR LEGAL MATTERS

DECREE NO. 6,233, OF OCTOBER 11, 2007

Establishes criteria for qualification into the Semiconductor Industry Technological Development Support Program – PADIS, granting exemption from income tax and reducing to zero the rate of PIS/PASEP and COFINS contributions and IPI tax, established by Articles 1 and 11 of Law no. 11,484, of May 31, 2007.

THE PRESIDENT OF THE REPUBLIC, using the powers vested in him under Article 84(IV) of the Federal Constitution, and in view of Articles 1 to 11 of Law no. 11,484, of May 31, 2007,

DECREES:

CHAPTER I

SEMICONDUCTOR INDUSTRY TECHNOLOGICAL DEVELOPMENTAL
SUPPORT PROGRAM – PADIS

Article 1. The Semiconductor Industry Technological Development Support Program – PADIS shall be implemented under the form established in this Decree.

Article 2. PADIS reduces to zero the rates:

- I - of Contribution to PIS/PASEP and Contribution to the Social Security Funding – COFINS, charged on the gross revenue resulting from the sale, in the domestic market, to a legal entity qualified in PADIS, of the following products:
 - (a) machinery, apparatus, instruments, equipment, new, to be incorporated to fixed assets of the purchaser, turned to activities mentioned by Article 6 and Article 6(I) and (II) hereof; and
 - (b) computational tools (software) and inputs for activities mentioned by Article 6 and Article 6(I) and (II) hereof;
- II - of Contribution to PIS/PASEP – Import and COFINS – Import charged on imports, performed by a legal entity qualified in PADIS, of the following products:
 - (a) machinery, apparatus, instruments, equipment, new, to be incorporated to fixed assets of the purchaser, turned to activities mentioned by Article 6 and Article 6(I) and (II) hereof; and
 - (b) software and inputs for activities mentioned by Article 6

and Article 6(I) and (II) hereof;

- III - of the Excise Tax – IPI, charged on imports performed by a legal entity qualified in PADIS, or on the exit from the industrial or similar establishment, based on purchases made in the domestic market by a legal entity qualified in PADIS, of the following products:
- (a) machinery, apparatus, instruments, equipment, new, to be incorporated to fixed assets of the purchaser, turned to activities mentioned by Article 6 and Article 6(I) and (II) hereof; and
 - (b) software and inputs for activities mentioned by Article 6 and Article 6(I) and (II) hereof.

Paragraph 1. For the purposes of this Article 2, a legal entity purchaser of foreign goods, in case of import performed on the legal entity's own account through a legal entity that is an importer, is equivalent to an importer.

Article 3. The rate of the contribution to intervention in the economic domain – CIDE targeted to finance the University – Enterprise Interaction Incentive Program, mentioned by [Article 2 of Law no. 10,168, of December 29, 2000](#), is reduced to zero (0) in remittances abroad for the payment of agreements related to exploitation of patents or use of trademarks and supply of technology and technical assistance, when carried out by a legal entity beneficiary of PADIS and linked to activities mentioned by Article 6(I) and (II) hereof.

Article 4. In sales of semiconductor electronic devices and displays mentioned on Article 6(I) and (II) hereof, respectively, conducted by legal entity beneficiary of PADIS, the following rates are reduced:

548/2008

- I - to zero, the rates of the PIS/PASEP and COFINS contributions charged on revenues earned;
- II - to zero, the rates of IPI tax charged upon exit of the industrial facility;
- III - in one hundred percent (100%) the rates of income and additional tax charged on export profits.

Paragraph 1. Reductions in rates mentioned in this Article 4(I) and (III) shall apply, additionally, to revenues earned in the sale of designs, when conducted by a legal entity beneficiary of PADIS.

Paragraph 2. The reductions mentioned in this Article 4 shall not apply cumulatively with other reductions of benefits related to the same tax or contribution, except for the provisions of [Article 17\(I\) and Paragraph 2 of such Article of Law no. 11,196, of November 21, 2005](#).

CHAPTER II

QUALIFYING FOR PADIS

Section I

Mandatory Character of Qualification

Article 5. Only legal entities previously qualified by the Brazilian Federal Revenue Secretariat – RFB may benefit from PADIS.

Section II

Legal Entities Eligible to Apply for Qualification

Article 6. The qualification mentioned by Article 5 hereof may be applied for by a legal entity that conducts investments in research and development -R&D under Article 8 hereof, and that performs, either individually or jointly, related to:

548/2008

- I - electronic semiconductors, classified in headings 85.41 and 85.42 of the Common Mercosul Nomenclature – NCM mentioned in the Annex I to this Decree, the following activities:
 - (a) conception, development and design;
 - (b) diffusion or physic-chemical processing; or
 - (c) incapsulation and tests;
- II - displays mentioned in Paragraph 1 of this Article 6, the following activities:
 - (a) conception, development and design;
 - (b) manufacturing of photosensitive, photo- or electroluminescent elements and light emitters; or
 - (c) final display assembly and electrical and optical tests.

Paragraph 1. The provisions of this Article 6(II) are:

- I - applicable only to displays mentioned in Annex I to this Decree, with technology based on liquid crystal (LCD), photoluminescent (plasma display panel – PDP) and electroluminescent (light-emitting diodes – LED, organic light emitting diodes – OLED, or thin film electroluminescent display – TFEL) components; or similar components embedding electric field emitting microstructures, targeted as inputs for electronic equipment; and
- II - not applicable to cathode ray tubes (CRT).

Paragraph 2. For the purposes of this Article 6, it is deemed that the legal entity performs its activities:

- I - separately, when it conducts all steps envisaged by the letters,

548/2008

(a), (b) or (c), of this Article governing such legal entity;

- II - jointly, when it conducts all steps envisaged by the item, (I) or (II) of this Article governing such legal entity.

Paragraph 3. A legal entity referred to in this Article 6 shall perform, exclusively, the activities envisaged in this Article 6.

Paragraph 4. The investment in research and development mentioned in this Article 6 and activities mentioned in this Article 6(I) and (II) shall be conducted under the projects approved according to Article 7 hereof.

Section III

Approval of Projects

Article 7. Projects mentioned in Paragraph 4 of Article 6 hereof shall be approved in a joint Resolution of the Minister of State of Finance, Minister of State of Science and Technology and Minister of State of Development, Industry and Foreign Trade.

Paragraph 1. Approval of the project mentioned in this Article 7 depends on:

- I - evidence of fiscal regularity of the interested legal entity, regarding taxes and contributions managed by the Brazilian Federal Revenue Secretariat;
- II- compliance with instructions established in a joint Resolution of the Minister of State of Science and Technology and Minister of State of Development, Industry and Foreign Trade; and
- III - previous verification, by the Brazilian Federal Revenue Secretariat, under terms and conditions to be established in an appropriate act, of compliance of the assets submitted by the qualified legal entity with the Annexes of this Decree.

548/2008

Paragraph 2. The term for submission of projects is four (4) years from the date of publication of this Decree, extendable for four (4) years in an act of the Executive Branch.

Paragraph 3. Procedures and terms for assessment of projects shall be established by joint Directive of the Minister of State of Finance, Minister of State of Science and Technology and Minister of State of Development, Industry and Foreign Trade.

Paragraph 4. The joint Directive mentioned by this Article 7 shall establish input-output or input-production ability criteria in a way to harmonize the purchases of goods mentioned in the Annex to this Decree to the using capacity of the legal entity qualified on the activities mentioned in Article 6 hereof.

Section IV

Investment in Research and Development

Article 8. A legal entity beneficiary of PADIS, mentioned in Article 6 hereof, shall invest, on an yearly basis, in research and development activities conducted within Brazil, not less than five percent (5%) of its gross revenues earned in the domestic market, net of taxes incident on the marketing of devices mentioned in Article 6(I) and (II) hereof and the value of purchases of products benefited by PADIS incentives.

Paragraph 1. Eligible investments are those made in areas of microelectronics in activities of research and development of devices mentioned in Article 6(I) and (II) hereof; optoelectronic devices; software; support to such projects; and design and process methodologies of components mentioned in Article 6(I) and (II) hereof.

Paragraph 2. Not less than one percent (1%) of the gross revenue, net of taxes incident on the marketing, as mentioned by this Article 8, shall be invested

through agreements with Brazilian research centers or institutions, of with official or recognized educational institutions, accredited by the Information Technology Area Committee – CATI, mentioned by [Article 30 of Decree no. 5,906, of September 26, 2006](#), or by the Amazon Research and Development Activities Committee – CAPDA, mentioned by [Article 26 of Decree no. 6,008, of December 29, 2006](#).

Paragraph 3. An intellectual property resulting from research and development conducted through projects in the context of PADIS shall have its protection as applied for, in the Brazilian territory, before the appropriate agency, as the case may be, by the Brazilian legal entity beneficiary of PADIS.

Article 9. A legal entity beneficiary of PADIS shall forward to the Ministry of Science and Technology, not later than July 31 each year, reports showing compliance, in the previous calendar year, with the obligations and conditions laid down by Article 8 hereof.

Article 10. In case investments in research and development envisaged in Article 8 hereof fail to reach, in a certain calendar year, the lowest percentage established, the legal entity beneficiary of PADIS shall invest the residual amount in the Science and Technology Development National Fund – FNDCT (CT-Info or CT-Amazon), plus a fine of twenty percent (20%) and interests at a rate equivalent to the rate of the Special Settlement and Custody System - SELIC, calculated from January 1st of the year subsequent to that in which the percentage failed to be reached to the date of effective investment.

Paragraph 1. A legal entity beneficiary of PADIS shall make the investment mentioned in this Article 10 above not later than the last day of March of the year subsequent to the one in which the percentage was not met.

Paragraph 2. In the case mentioned in this Article 10, failure to conduct the

548/2008

investment within the term determined in Paragraph 1 above subjects the taxpayer to pay:

- I - interests and arrears, under applicable legislation, on contributions and taxes unpaid according to provisions of Article 4(I) and (II); and
- II - income and additional taxes unpaid according to the provisions of Article 4(III), and interests and arrears, under applicable legislation.

Paragraph 3. Interests and arrears mentioned by Paragraph 2(I) of this Article 10 shall be paid separately and shall be calculated:

- I - from the effective date of sale, in case of Article 4(I), or from the date in which the product exits the industrial facility, in case of Article 4(II); and
- II - on the amount of unpaid contributions and taxes, in proportion to the difference between the lowest percentage of the established investment in research and development and the investment effectively made.

Paragraph 4. Payments made under Paragraphs 2 and 3 do not preclude a legal entity beneficiary of PADIS from the duty of make investments in FNDCT (CT-Info or CT-Amazon), as envisaged by this Article 10, in addition to arrears and interests mentioned thereby.

Paragraph 5. Lack or irregularity in payments mentioned by Paragraph 2 above, subjects the legal entity to be charged *ex-officio* with application of *ex-officio* fine under applicable legislation.

Paragraph 6. Lack of compliance with the provisions of this Article 10 subjects the legal entity to the provisions of Article 11 hereof.

CHAPTER III

SUSPENSION AND CANCELLATION OF PADIS QUALIFICATION

Article 11. A legal entity beneficiary of PADIS may be punished, at any time, with suspension of the benefits envisaged by Articles 2 to 4 hereof, without prejudice of specific penalties, in case the legal entity:

- I - fails to submit the reports mentioned by Article 9 hereof, or such reports fail to be granted approval;
- II - fails to make the investments in research and development prescribed by Article 8 hereof, under the provisions of Article 10 hereof;
- III - fails to comply with its obligations mentioned in Paragraph 3 of Article 8 hereof;
- IV - incurs in irregularity in the payment of any tax or contribution managed by the Brazilian Secretariat of Federal Revenue; and
- V - uses the goods listed in the Annexes of this Decree in activities other than those described in Article 6 above, according to input-output or input-production capacity criteria mentioned in Paragraph 4 of Article 7 hereof.

Paragraph 1. The suspension mentioned in this Article 6 shall be changed into cancellation of application of benefits envisaged by Articles 2 to 4 hereof in case the legal entity beneficiary of PADIS fails to remedy the default within ninety (90) days from the date the suspension is notified.

Paragraph 2. A legal entity that gives cause to two (2) suspensions within a period of up to two (2) calendar years shall be penalized with cancellation of the benefits envisaged by Articles 2 to 4 hereof.

548/2008

Paragraph 3. The penalty of cancellation of benefits may be reverted not earlier than two (2) calendar years from the date in which the violation causing the cancellations is remedied.

Article 12. The suspension of cancellation, as the case may be, shall be formalized in an act by the Brazilian Secretariat of Federal Revenue.

CHAPTER IV

APPLICATION OF PADIS

Article 13. The benefit of reduced rates mentioned by Article 2 hereof applies only to the following imports and/or purchases in the domestic market:

- I - machinery, apparatus, instruments and equipment, new, listed in Annex II to this Decree;
- II - inputs listed in Annex III to this Decree; and
- III - software listed in Annex IV to this Decree.

Article 14. In case of purchase of goods in the domestic market with the benefits of PADIS, the legal entity who sells shall include in the bill of sale the expression "Sale to legal entity qualified with PADIS, made with reduction to zero of the rate of Contribution to PIS/PASEP, COFINS and IPI", specifying the corresponding legal permission, as well as the number of the act granting such qualification to the purchaser.

Article 15. Reduction in rates envisaged in Article 4(I) and (II), related to sales of displays mentioned in Article 6(II) hereof apply only in case:

- I - the display conception, development and design have been developed within Brazil; and
- II - the manufacture of photosensitive, photo- or electroluminescent elements, and light emitters has been conducted within Brazil.

548/2008

Article 16. The amount of income tax and additional tax left unpaid by virtue of the reduction mentioned by Article 4(III) may not be distributed to stockholders and shall be credited to the capital reserve of the legal entity and may only be used in offsetting losses or increasing stock capital.

Paragraph 1. The following is deemed to be a distribution of the tax amount:

- I - restitution of capital to partners, in case of capital stock reduction, up to the amount of the increase by incorporation of capital reserves; and
- II - distribution of net assets of the dissolved legal entity, up to the capital reserve balance.

Article 17. To exercise the benefit of rate reduction mentioned by Article 4(III), a legal entity shall display in its accounting books, clearly and accurately, the elements establishing revenues, costs, expenditures and results of the assessment period, related to sales benefited by the reduction, segregated from the remaining activities of the legal entity.

Article 18. Lack of compliance with the provisions of Articles 16 and 17 hereof subjects the legal entity to loss of the right to reduction in rates mentioned by Article 4(III) hereof and payment, as regard the distributed amount, of the tax left unpaid by the legal entity, plus interests and arrears according to applicable legislation.

CHAPTER V

GENERAL PROVISIONS

Article 19. The Ministry of Science and Technology shall notify the Brazilian Federal Secretariat of Federal Revenue any case of:

- I - lack of compliance, by the legal entity beneficiary of PADIS, with

548/2008

the obligation to forward the compliance reports within the term mentioned in Article 9 hereof, or with the obligation to invest in FNDCT (CT-Info or CT-Amazon), according to Article 10 hereof, under the term established by Paragraph 1 of such Article 10, when the minimum percentage of investment in research and development had not been reached.

- II - lack of approval of the compliance reports mentioned by Article 9; and
- III - violation of any provision of this Decree.

Paragraph 1. Cases foreseen in this Article 19(I) shall be notified not later than August 20 each calendar year, and the remaining cases within thirty days from the event.

Article 20. The Ministry of Science and Technology, Ministry of Development, Industry and Foreign Trade shall publish, each three calendar years, reports on the economic and technological results brought by the application of the provisions of this Decree.

Paragraph 1. The Ministry of Finance, Ministry of Science and Technology and Ministry of Development, Industry and Foreign Trade shall publish, each calendar year, the modalities and amounts of incentives granted and investments made in Research and Development, by banking institution and project, in a form to be defined in a joint Directive of the respective Ministers of State.

Article 21. Without prejudice of the provisions of Article 9 hereof, the Brazilian Secretariat of Federal Revenue shall establish, in an appropriate act, the need to submit, within a definite term, the periodic statements showing the input-output relations of goods benefitted by PADIS, for the purpose of monitoring and control.

CHAPTER VI

FINAL PROVISIONS

Article 22. The provisions of this Decree shall not exclude the competence of consenting agents in what regard the freeing and control of goods listed in the Annexes hereof.

Article 23. The provisions of Article 2 and Article 4(I) and (II) shall be effective up to January 22, 2022.

Article 24. The provisions of Article 3 and Article 4(III) shall be effective for:

- I - sixteen (16) years from the date of project approval, in case of projects related to activities mentioned in:
 - (a) Article 6(I)(a) and (b); and
 - (b) Article 6(II)a) or (b);
- II - twelve (12) years from the date of project approval, in case of projects related only to activities mentioned in:
 - (a) Article 6(I)(c); and
 - (b) Article 6(II)(c).

Article 25. The Brazilian Secretariat of Federal Revenue shall control, in its jurisdiction, application of the provisions of this Decree, including the qualifying procedures.

Article 26. This Decree shall be effective upon publication.

Brasília, October 11 2007, 186th of the Independence and 119th of the Republic.

LUIZ INÁCIO LULA DA SILVA

Guido Mantega

548/2008

Miguel Jorge

Sérgio Machado de Rezende.

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548/2008

ANNEX I

Final Products

Semiconductor electronic devices	NBN
Diodes, transistors and similar semiconductor devices; photosensitive semiconductor devices, including photovoltaic cells whether or not assembled in modules or made up into panels; light emitting diodes; mounted piezoelectric crystals	8541
Electronic integrated circuits	8542

Displays	NCM
Plasma devices	8529
Displays build from OLED of position 8541	--
Displays built from TFED of headings 8541 and 8542	--
Liquid crystal devices (LCD)	9013.80.10

548/2008

ANNEX II

Machinery, apparatus, instruments and equipment, to be incorporated to fixed assets and to be used in activities aimed at final products

548/2008

Description	NCM
Plastic tanks	3925
Stainless steel tanks, capacity exceeding 300 liters	7309.00
Stainless steel tanks, capacity limited to 300 liters	7310
Containers for storage of gases	7311
Pumps	8413
Pump parts	8413.91
Vacuum pumps	8414.10.00
Compressors	8414
Air pumps	8414
Vacuum pump and compressor parts	8414.90
Functional units for air conditioning and refrigeration in "clean rooms"	8415
Electric laboratory furnaces	8417
Distillation apparatuses	8419.40
Heat pumps	8419.50
Electric heaters	8419.89.20
Heating plates	8419
Evaporators	8419.89.40
Parts of distillers, heat pumps, heaters and evaporators	8419.90
Liquid filtering or purifying machinery	8421.2
Gas filtering or purifying machinery	8421.3
Parts of liquid or gas filtering or purifying machinery	8421.9
Polarizer application and removal machinery	8424
Sand blasting machinery for structure formation in inorganic substrata	8424
Machine tools that operate through removal of any material	8456
Automatic data processing machinery under the form of systems	8471.49

548/2008

Description	NCM
Automatic data processing machine input or output units, either embedding memory units or not	8471.60
Automatic data processing machinery memory units	8471.70
Parts and accessories of machinery of heading 8471	8473.30
Machinery for manufacturing or hot working glass or glassware	8475.2
Machinery for polymer lamination	8477
Injection molding machinery	8477.10
Extruders	8477.20
Insufflation molding machinery	8477.30
Vacuum molding and other thermoforming machinery	8477.40
Stamping machinery for structure engraving in organic materials	8479
Industrial robots	8479.50.00
Electrical and/or electronic component positioning machinery	8479
Agitators	8479.82.10
Ultrasound cleansing equipment	8479.89.91
Glove boxes	8479
Silk screen machinery and equipment	8442
Parts of silk screen machinery and equipment	8442.40
Valves	8481
Valve parts	8481.90
Gaskets and joints	8484
Machinery and apparatus of the type used either exclusively or mainly for the manufacture of boules or wafers of semiconductor devices for the production of electronic integrated circuits or flat screen displays	8486
Machinery and apparatus specified in NCM Chapter 84, Note 9C; Parts and accessories	8486

548/2008

Description	NCM
Parts and accessories	8486.90.00
Electric engines	8501
Electrical transformers, static converters, reactance and auto-inducing coils	8504
Boards, panels, consoles, desks, cabinets and other bases, equipped with two or more apparatus of heading no. 8535 or 8536, for electric control or the distribution of power (including those incorporating instruments or apparatus of NCM Chapter 90) to operate in a tension not exceeding 1,000 V	8537
Parts of lamps	8539
Optical microscopes	9011
Parts and accessories of optical microscopes	9011.90
Electronic microscopes	9012
Parts and accessories of electronic microscopes	9012.90
Instruments and apparatus for measuring or checking the flow, level, pressure or other variable characteristics of liquids or gases	9026
Instruments and apparatus for physical or chemical analysis (for example, polarimeters, refractometers, spectrometers, gas or smoke analysis apparatus).	9027
Oscilloscopes, spectrum analyzers, and other instruments and apparatus for measuring or checking electrical quantities.	9030
Instruments, machinery and apparatus for measuring and controlling wafers or semiconductor devices or controlling masks or reticles used in the manufacture of semiconductor devices	9031.41
"Helium leak testing" set	9031.80.99

548/2008

ANNEX III

Inputs used in activities leading to final products

548/2008

Description	NCM
Chloride	2801.20.00
Hydrogen	2804.10.00
Helium	2804.29
Argon	2804.21.00
Nitrogen	2804.30.00
Oxygen	2804.40.00
Silicon, non doped	2804.61.00
Phosphor, suitable for field emission displays and CCFL and EEFL lamps	2804.70
Hydrochloric acid	2806.10
Sulfuric acid	2807.00
Nitric acid	2808.00.10
Phosphoric acid	2809.20.1
Fluoridric acid	2811.11.00
Hydroxilamine	2825.10.20
Hydrogen bromide	2811.19.90
Nitrous oxide	2811.29.90
Boron trichloride	2812.10.19
Silicon tetrachloride	2812.10.19
Tin tetrachloride	2812.10.19
Phosphor oxychloride	2812.10.22
Nitrogen trifluoride	2812.90.00
Sulfur hexafluoride	2812.90.00
Carbon dioxide	2811.21.00
Boron trifluoride	2812.90.00
Boron tribromide	2812.90.00
Ammonia (ammoniac gas)	2814.10.00

548/2008

Description	NCM
Ammonia hydroxide	2814.20.00
Antimony trioxide	2825.80.10
Ammonia fluoride	2826.19.90
Tungsten hexafluoride	2826.90.90
Titanium tungstate	2841.80.90
Precious metals solutions in colloidal state	2843.10.00
Hydrogen peroxide	2847.00.00
Phosphine (hydrogen phosphide or phosphorus hydride)	2848.00.90
Arsine	2850.00.90
Diborane	2850.00.90
Dichloromethane (methylene chloride)	2903.12.00
Trimethylphosphite (dimethyl methylphosphonate)	2931.00.90
Trimethylborate (dimethyl methylborate)	2931.00.90
Triethylphosphate (dimethyl methylphosphate)	2931.00.90
Methyl fluoride	2903.39.19
Hexafluorethane	2903.39.19
Fluoromethane	2903.39.19
Trifluoromethane	2903.39.19
Trifluoroethane	2903.39.19
Tetrafluoromethane	2903.39.19
Difluoromethane	2903.39.19
Trichlorofluoromethane	2903.41.00
Octafluorocyclobutane	2903.59.90
Ethylenoglycol	2905.31.00
Methanol	2905.11.00
Isopropyl alcohol	2905.12.20
n-Butyl alcohol	2905.13.00

548/2008

Description	NCM
Methoxyethanol (ethylene glycol monoethyl ether)	2909.49.29
Butylic acetate	2915.33.00
Acetone	2914.11.00
Acetic acid	2915.21.00
Monoethanolamine	2922.11.00
Tetramethylammonium hydroxyde	2823.90.90
Dimethylacetamide	2924.29.49
Silane	2931.00.29
Dichlorosilane	2931.00.29
Tetramethylsilane	2931.00.29
Tetramethylcyclotetrasiloxane	2931.00.29
Hexamethyldisilane	2931.00.29
Tetraethylorthosilicate	2931.00.29
Trimethylphosphate	2931.00.39
Tin isopropoxide	2931.00.49
Aluminum lactate	2931.00.69
Titanium isopropoxide	2031.00.90
Trimethylborate	2931.00.90
n-Methyl-2-Pyrrolidone	2933.79.90
Glass fries	3207.40.10
Adhesives for displays	3506
Preparations for metal pickling	3810.10.10
Soldering pastes and powders	3810.10.20
Soldering flows	3810.90.00
Preparations for filling or recovering of electrodes or soldering rods	3810.90.00
Organic solvents and dilutors, non specified nor contained in other	3814.00.00

548/2008

Description	NCM
headings	
Preparations designed to remove paint or varnish	3814.00.00
Type p monocrystalline silicon blades, doped with boron (B), with epitaxial layer or otherwise, and crystalline orientation of <111> or <100>	3818.00.10
Monocrystalline silicon blades, doped with phosphor, arsenic or antimony, with epitaxial layer or otherwise, and crystalline orientation of <111> or <100>	3818.00.10
Quartz substrate, in the form of cookies	3818.00.90
Photonic devices substrate, in the form of cookies	3818.00.90
Phosphine and nitrogen mixture	3824.90.79
Arsine and hydrogen mixture	3824.90.79
Hydrogen and nitrogen mixture	3824.90.79
Oxygen and helium mixture	3824.90.79
Diborane and nitrogen mixture	3824.90.79
Phosphine and silane mixture	3824.90.79
Photoresist developer	3824.90.79
Tamponated oxide remover, made of a mixture of ammonium fluoride, fluoridic acid and water	3824.90.79
Nanostructured materials based on organic compounds	3824.90.79
Mixture of ammonium fluoride and phosphoric acid, in water	3824.90.79
Mixture of tetrafluoromethane in oxygen	3824.90.89
Mixture of monoethanolamine, hydroxylamine and pyrocatechol, in water	3824.90.89
“Organic photoresist” (solution of polymer or epoxy resin in organic solvent)	3824.90.89

548/2008

Description	NCM
Mixture of phosphoric acid, nitric acid and acetic acid, without surfactant	3824.90.89
Mixture of phosphoric acid, nitric acid and acetic acid, with surfactant	3824.89.90
Materials nanostructured in carbon	3824.89.90
Liquid crystals, including thermotropic and lyotropic crystals	3824.90.89
Nanostructured materials based on organic compounds	3824.90.89
Chemical compounds to entrapment of residual gases ("getters")	3824.90
Poly (methylmetacrylate) (PPMA)	3906.10.00
"Perfluorated polyethers" type polymers, used as vacuum pump oils	3907.20.90
Epoxy resin	3907.30
Poly (dimethylglutarimide) (PMGI)	3911.90.29
Polyimides	3911.90.29
Plastic tubes and accessories	3917
Self-adhesive plates, sheets, film, foil, tape, strip and other flat shapes, of plastics, whether or not in rolls, width over 20 centimeters	3919.90.00
Plastic plates, covered by transparent films and energy conductors	3926
Circular cross-section rings ("O-rings")	3926.90.6
Graphite-made refractory ceramic products	6903
Quartz tubes, unworked	7002.31.00
Lamp bulbs	7011
Laboratory glassware	7017
Glass tablets	7020.00
Quartz tubes, worked	7020.00.90
Sapphire windows	7103.91.00

548/2008

Description	NCM
Diamond windows	7104.20.10
Other synthetic or reconstructed materials with piezoelectric properties, in plates or sheets.	7104.20.90
Diamond power for surface polishing	7105
Gold, including platinum gold, in powder, in crude or semi-manufactured form	7108
Platinum powder, in crude or semi-manufactured form	7110.1
Palladium powder, in crude or semi-manufactured form	7110.2
Stainless steel tubes	7304
Accessories for stainless steel tubes	7307
Cooper alloys for soldering	7405
Nickel alloys for soldering, in bars, profiles or wires	7505
Nickel powders and scales, either bonded or otherwise	7504.00
Nickel wires, either bonded or otherwise	7505.2
Tubes made of nickel alloys	7507.12.00
Silicon and aluminum plates, with copper or silicon and copper, for use in cathode bombarding deposition equipment	7606.12
Zinc, unbonded	7901.1
Tungsten (Wolframite) and articles thereof, including offscourings and refuse	8101
Molybdenum and articles thereof, including offscourings and refuse	8102
Cobalt plate to be used in cathode bombarding deposition equipment	8105.90.10
Titanium and articles thereof, including offscourings and refuse	8108
Titanium plates to be used in cathode bombarding deposition	8108.90.00

548/2008

Description	NCM
equipment	
Wires, rods, plates and slabs made of nickel, iron and cobalt alloys, "Kovar" type	8311
Beryllium windows	8112.19.00
Chromium	8112.2
Niobium and articles thereof, including offscourings and refuse	8112.9
Saw discs	8208.90.00
Parts used in displays	8529
Connectors for displays	8536
Stamped coverings for electronic components	8541.90.90
Ceramic coverings for electronic components	8541.90.90
Top lid of coverings for electronic components	8541.90.90
Starting integrated circuits for displays	8542
Titanium nitride plates to be used in cathode bombarding deposition equipment	8543.90.90
Microspacers of dielectric, organic or inorganic materials, for separating displays' glass plates	8546
Masks or reticules of glass or quartz, for photoengraving, impression in metal or composite film, for use in contact, projection or repetition aligners	9002.90.00

ANNEX IV

Software for use in activities linked to final products

DESCRIPTION	NCM
EDA ("Electronic Design Automation") type or similar computer programs that are used in the design of integrated circuits and are part of CAE/CAD/CAM tools.	---
"IP cores" type of similar computer programs, containing pre-programmed and tested design elements, that perform specific operations used in the design of integrated circuits	---
ISE/TCAD "Suprem" or similar process simulators performing simulations of physicochemical processing phases, used in the production and/or production management of integrated circuits	---
"Prolith" type or similar photolithography simulators, used in the process of production and/or production management of integrated circuits	---
Programs for extraction of electrical parameters and modeling, used in the process of production and/or production management of integrated circuits	---
Programs for electric measurements, used solely and specifically in the process of production and/or production management of integrated circuits	---

DESCRIPTION	NCM
Program for defect analysis and interpretation, used solely and specifically in the process of production and/or production management of integrated circuits	---

548/2008

Program for defect analysis and interpretation, used solely and specifically in the process of production and/or production management of integrated circuits	---
Programs for plant automation used solely and specifically in the process of production and/or production management of integrated circuits	---
Programs for performance optimization, used solely and specifically in the process of production and/or production management of integrated circuits	---

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In Witness Whereof, I have hereunto set my hand and seal in this City of Brasília, Federal District, Brazil, this Monday, November 03, 2008.

Fees according to

Official Gazette of 11/10/2003

Page 098

Marco Antônio Rochadel

Public Translator